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<p>Substitute for form 1449A/PTO (Modified by BSTZ 6/30/99)</p> <p>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</p> <p><i>(use as many sheets as necessary)</i></p>				<i>Complete if Known</i>	
				Application Number	09/096,858
				Filing Date	June 12, 1998
				First Named Inventor	Narwankar et al.
				Group Art Unit	2814
				Examiner Name	Mai, A.
Sheet	1	of	1	Attorney Docket Number	2571.US/RTP/LE

U.S. PATENT DOCUMENTS

FOREIGN PATENT DOCUMENTS

Examiner Initials *	Foreign Patent Document			Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Translation? Yes/No
	Office or Country	Number	Date			
A.M	Japan	03212938 ✓	1/18/1990	Seiko Epson Corp	9/18/1991	Yes
	Japan	04362017 ✓	6/6/1991	Nikko Kyodo Co. Ltd.	12/15/1992	Yes
	Japan	04092423 ✓	8/8/1990	Hitachi Tokyo Electron Co. Ltd.	3/25/1992	Yes
	KR	9500861	2/2/1995	Hundai		Yes
	WO	95/26355 ✓	3/23/1995	Leedham et al	10/5/1995	Yes

OTHER DOCUMENTS

OTHER DOCUMENTS			
Examiner Initials *	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published (if known).	Translation? Yes/No	
A M	MFG. INSULATION LAYER OF CAPACITOR HAVING HIGH DIELECTRIC CONSTANT...Derwent Publications Ltd., London, GB XP002120114	Yes	
	"Low-temperature preparation of SiO ₂ /Si(100)interfaces using a two-step remote plasma-assisted oxidation-deposition process", Yasuda, Habermehi, and Lucovsky January 27, 1992 American	Yes	
	Institute of Physics pages 434-436		
	"Nitrogen plasma annealing for low temperature Ta ₂ O ₅ Films" Alers, Fleming, Wong, Dennis and Pinczuk. 1998 American Institute of Physics Lucent Technologies NJ pgs. 1308-1310	Yes	
	Enclosed copy of International Search Report	Yes	

**Examiner
Signature**

ANH D. MA

Date Considered

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***EXAMINER:** Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.